

This listing of claims will replace all prior versions, and listings of claims in the application:

Listing of Claims:

- 5 Claim 1 (currently amended): A cleaning system, mechanism for an image sensor package, the cleaning mechanism being cleaning the substrate and the frame layer arranged on the substrate of the image sensor to form a chamber between the frame layer and the substrate, the mechanism comprising:
 a combination of a substrate and a frame layer arranged on the substrate to form a chamber together with the substrate;
10 a sealed up body being formed with a cleaning room, wherein the substrate is disposed in the cleaning room and fixed to an upper portion of the sealed up body with the chamber facing downwards; and formed with frame layer being fixed on the top end of the cleaning room, then, the chamber of the substrate being faced down direction from the cleaning room;
15 a first cleaning device being mechanism, which is disposed in the cleaning room mounted on the bottom end of the cleaning room of the sealed up body, for ejecting a cleaner slantingly upwards to clean cleaning the chamber of the combination of the substrate and the frame layer. by cleaner.
20 Claim 2 (currently amended): The cleaning mechanism system according to claim 1, wherein the sealed up body includes a lower element, a periphery wall connected to the lower element, and an upper cover connected to the periphery wall, and the substrate is fixed to the upper cover.
25 Claim 3 (currently amended): The cleaning mechanism system according to claim 1, wherein further includes further comprising a vacuuming pump is arranged with disposed in the cleaning room and under the chamber of the combination of the substrate and the frame layer.
 Claim 4 (currently amended): The cleaning mechanism system according to claim 1, wherein the cleaner is nitrogen or carbon dioxide. - of the cleaning device

is N₂ or CO₂.

Claim 5 (currently amended): The cleaning ~~mechanism~~-system according to claim 1, wherein the cleaner-of the cleaning device is water.

Claim 6 (new): The cleaning system according to claim 1, further comprising
5 a second cleaning mechanism disposed in the cleaning room and opposite to the first cleaning mechanism.

Claim 7 (new): The cleaning system according to claim 6, further comprising
a vacuuming pump, which is disposed in the cleaning room and under the chamber of the combination of the substrate and the frame layer, wherein the
10 vacuuming pump has a sucking port for sucking the cleaner, and the sucking port is disposed between the first cleaning mechanism and the second cleaning mechanism.